

Title (en)  
Vacuum pump system

Title (de)  
Vakuumpumpsystem

Title (fr)  
Système de pompe à vide

Publication  
**EP 1441128 A2 20040728 (DE)**

Application  
**EP 03028333 A 20031210**

Priority  
DE 10302764 A 20030124

Abstract (en)  
The vacuum pump system (1) includes at least one high vacuum pump (3, 4). It has at least one intermediate pump (6) fitted directly and with low conductance loss on the ejection side of the high vacuum pump. There may be several intermediate pumps, which may be arranged in series or in parallel. At least one of them may have a suction capacity at least 50% that of the high vacuum pump.

Abstract (de)  
Vakuumpumpsystem zur Förderung leichter Gase mit wenigstens einer Hochvakuumpumpe, bei der an einer Ausstoßseite der wenigstens einen Hochvakuumpumpe wenigstens eine Zwischenpumpe direkt und mit geringem Leitwertverlust angeschlossen ist. <IMAGE>

IPC 1-7  
**F04D 27/00**; F04D 19/04; F04C 23/00

IPC 8 full level  
**F04D 19/04** (2006.01); **F04D 25/00** (2006.01); **F04D 27/00** (2006.01)

CPC (source: EP US)  
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